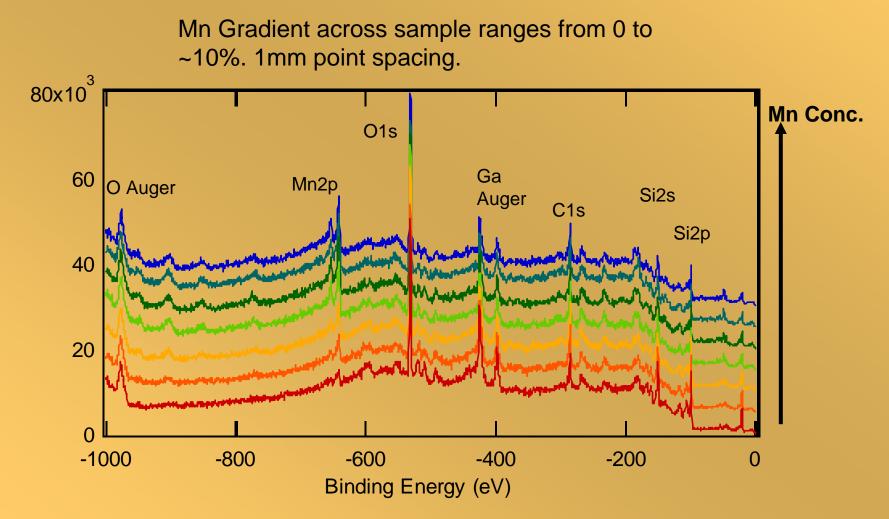
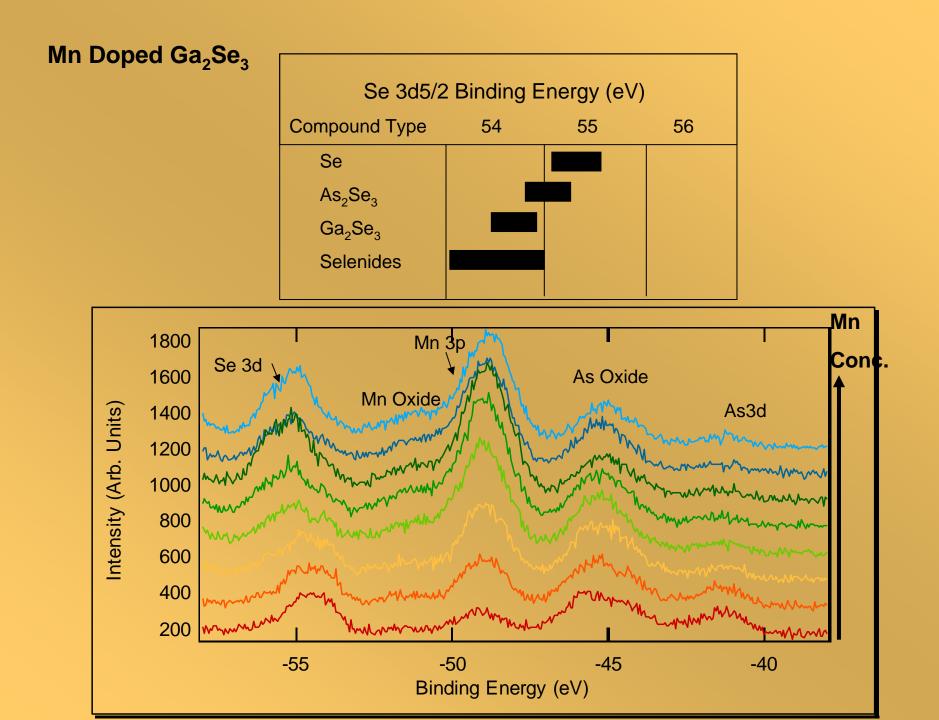
# **Mn-Doped Ga<sub>2</sub>Se<sub>3</sub>**

Samples examined were thin films of  $TM:Ga_2Se_3$  grown on an As-terminated Si wafer via Molecular Beam Epitaxy (MBE) at the Advanced Light Source ~1 year ago. Note Oxygen dominance, and presence of oxide peaks.



Intensity (Arb. Units)

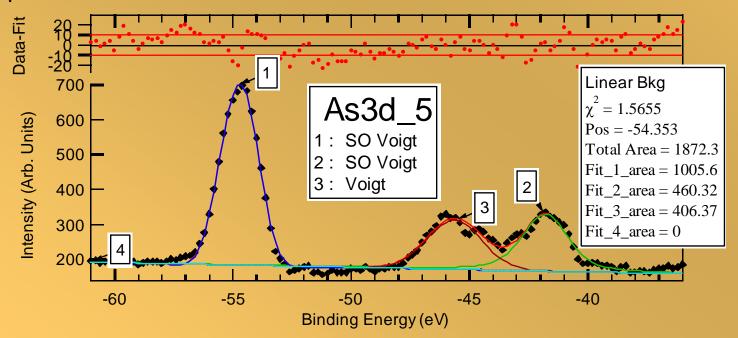


Towards Quantitative Analysis: Igor curve-fitting

Data are curve-fit in Igor Pro 5.0 to determine exact peak locations and areas.

The user can set parameters such as background and peak type, spinorbit splitting, etc.

Once this information is obtained, a more quantitative analysis can be performed.



## Water-Exposed Sample

To explore the resilience of the films, the surface of a 3-sectioned sample was covered in deionized water for ~1min

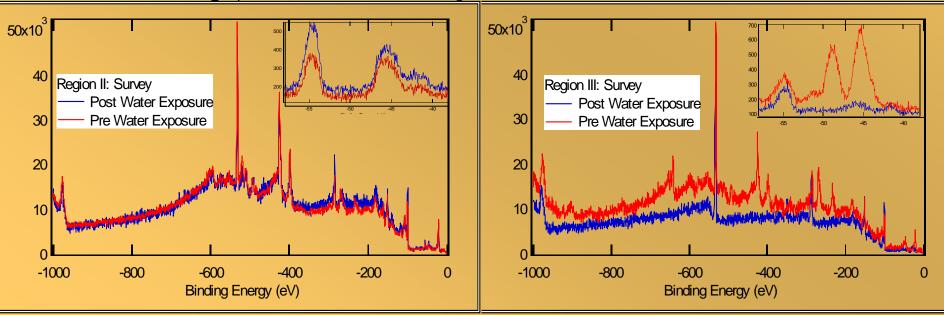
| Region I   | Region II | Region III   |
|------------|-----------|--------------|
| Si(100):As | Ga₂Se₃/Si | Mn:Ga₂Se₃/Si |

### Region II

Essentially unchanged by exposure. Also showed little change when exposed to acetone.

### **Region III**

Film mostly gone. Suggests that a particularly soluble Mn compound forms on the surface. Either  $Mn_2O_7$  (very soluble) or  $MnO_3$  (soluble)



#### Bake-out box

## Surface science and UHV

Surface sensitive techniques, such as XPS must be performed under Ultra-High Vacuum (UHV) conditions, as the slightest contamination will alter the results. Ambient pressures of <10<sup>-9</sup> Torr are considered in the UHV range.

## Pumping

Each type of pump operates over a limited range, so a combination is needed to reach UHV

## Baking

When exposed to air, a water film sticks to chamber walls. Baking the chamber for ~10hrs at 150-180C accelerates the evaporation of the film. The now gaseous contaminants are pumped out.

